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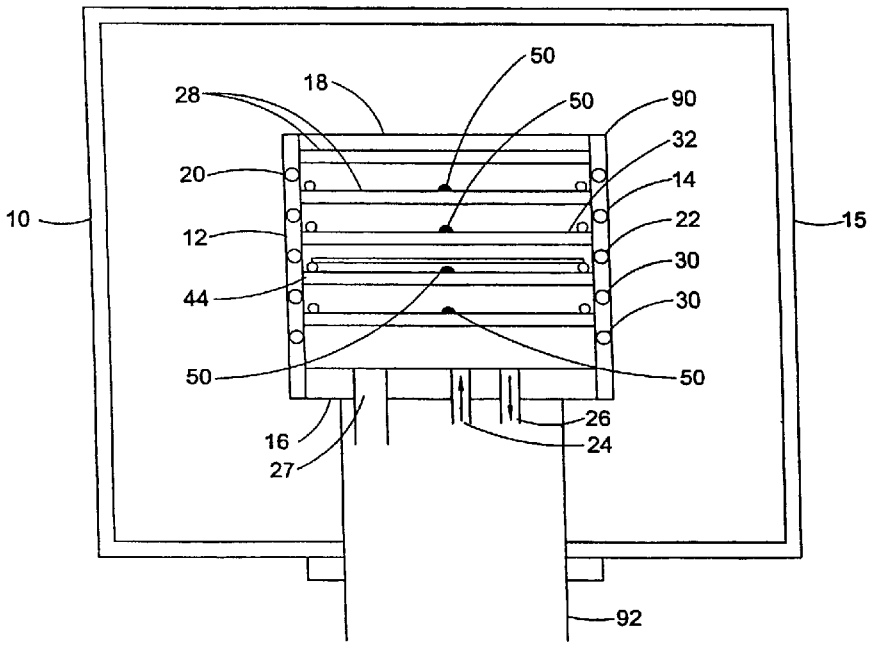
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(54) Title: SUBSTRATE SUPPORT



(57) Abstract: An apparatus for supporting a substrate is provided. In one embodiment, a substrate support is provided having a body and an upper portion having a socket and ball adapted to minimize friction and/or chemical reactions between the substrate support and the substrate supported thereon. The substrate supports may be utilized in various chambers such as load locks and chambers having thermal processes.

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